

4-11: A CMOS Image Sensor with A Stacked Photon Absorber for Wide-spectral Imaging

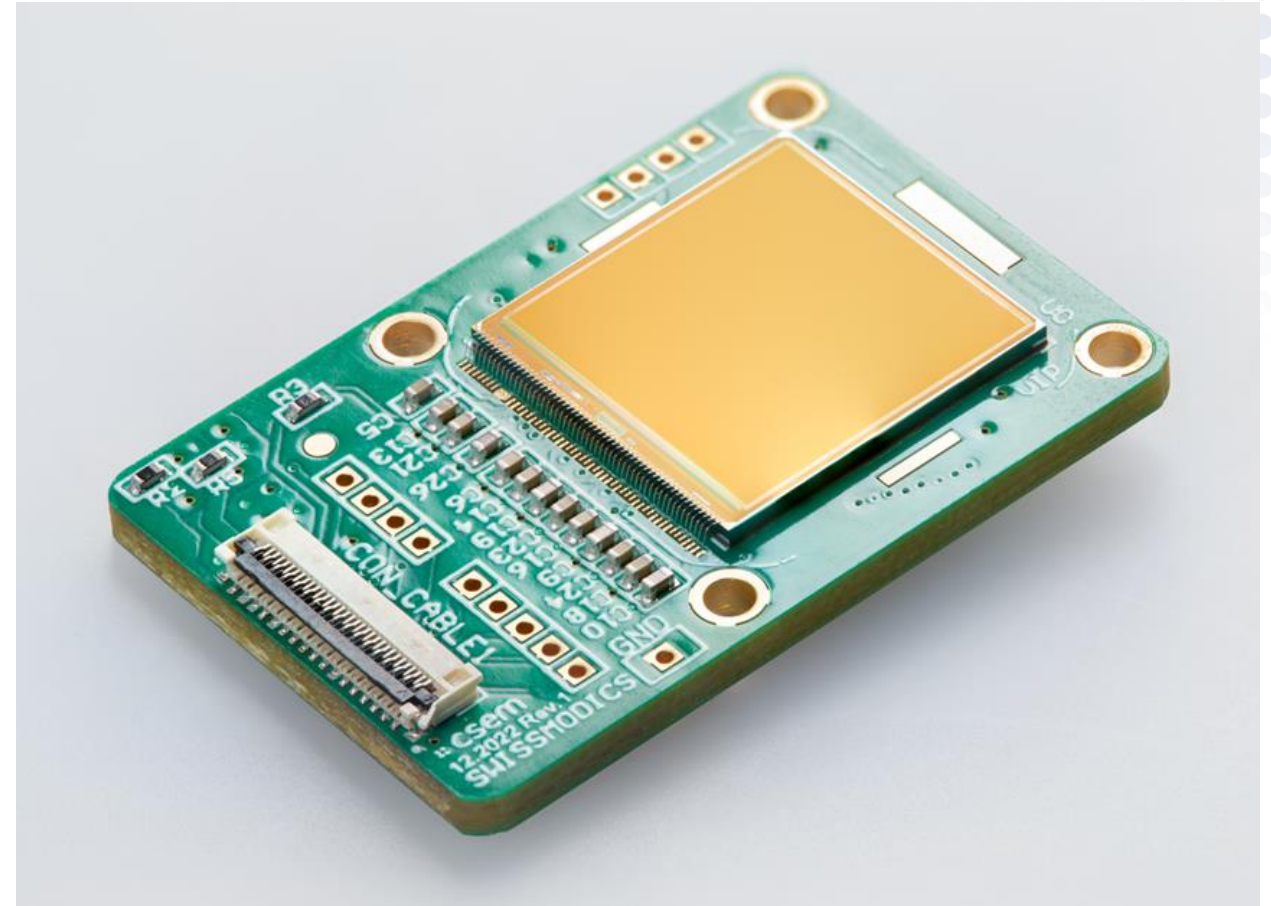
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Outline

- Context
- Proposed approach
- Step 1: readout chip design
- Step 2: Sensor development
- Conclusions



Context



Image Credit: News on Cornell.Edu

Impact on composite structures can generate long-distant delamination.

Defect detection requires immobilizing the aircraft.

How about more efficient diagnostic tools?

Inserting miniaturized cameras would ease the detection.

Context



Swissmodics: Development of a **S**ensor with **W**ide-**S**pectral **S**ensitivity for **M**onitoring of **D**amage and Defects **I**n **C**omposite Structures

- State-of-the-art

3D connection of photon absorbers to readout chips via bonding techniques

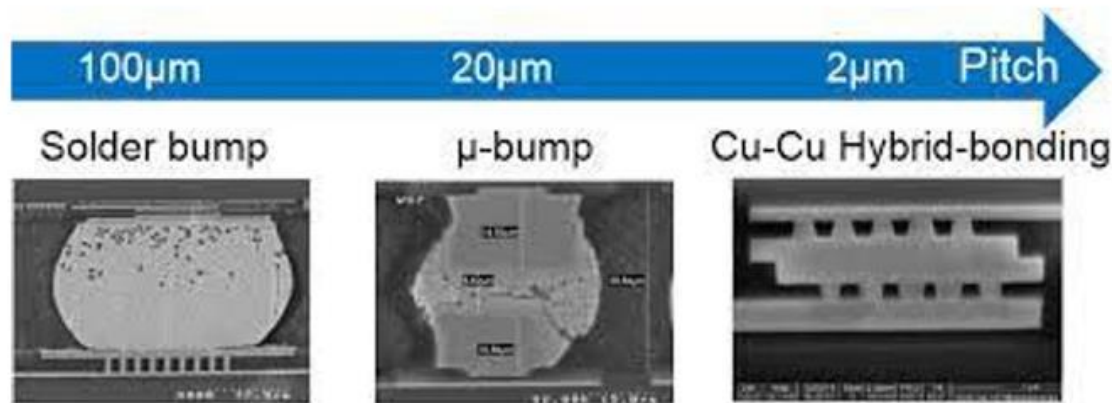
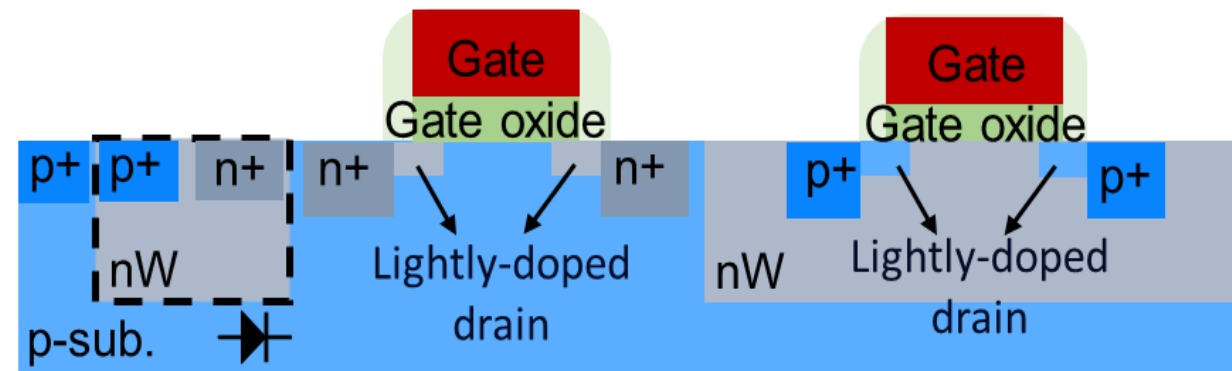


Image Credit: Imed Jani. Uni. Grenoble Alpes, 2019.

- Trend

Going towards monolithic detectors to reduce cost and increase resolution

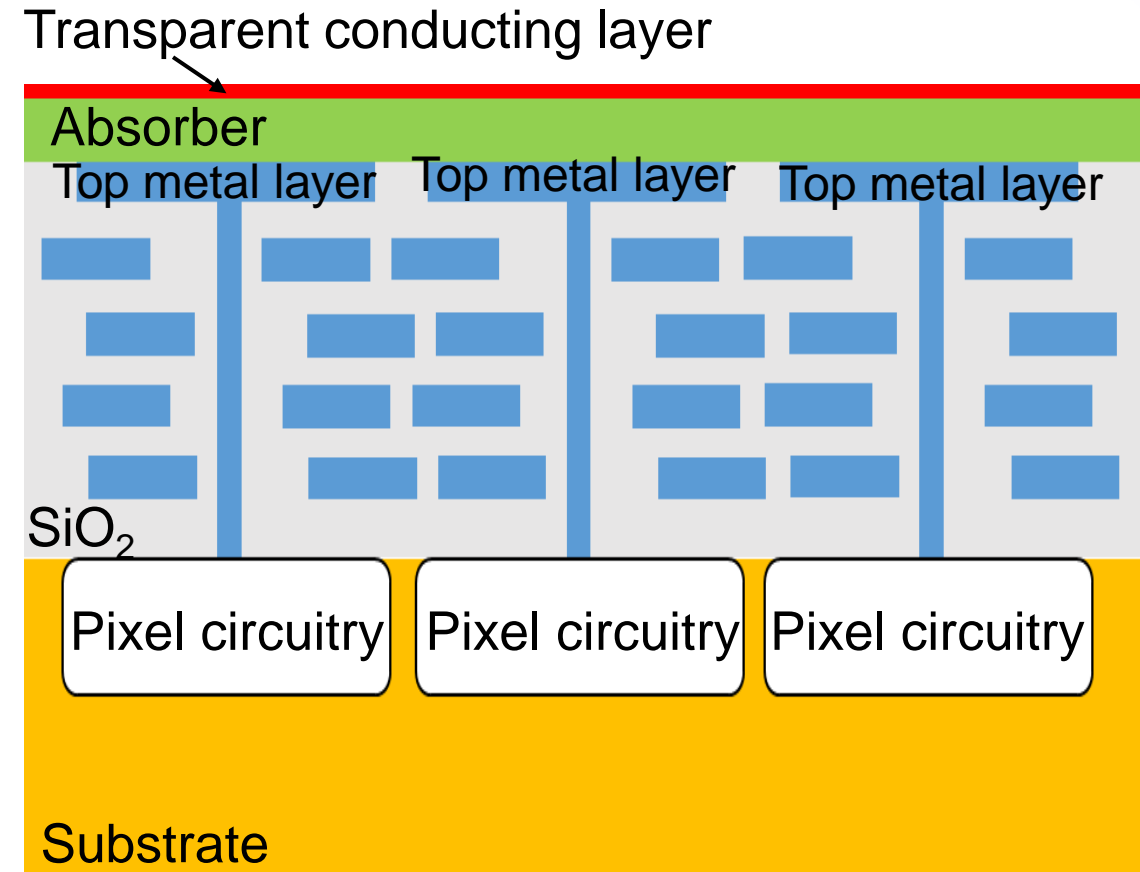


A simple sketch for a CMOS image sensor.

Proposed approach

3-D monolithic detectors with exotic sensing materials for X-ray, visible, and near-infrared (NIR) imaging

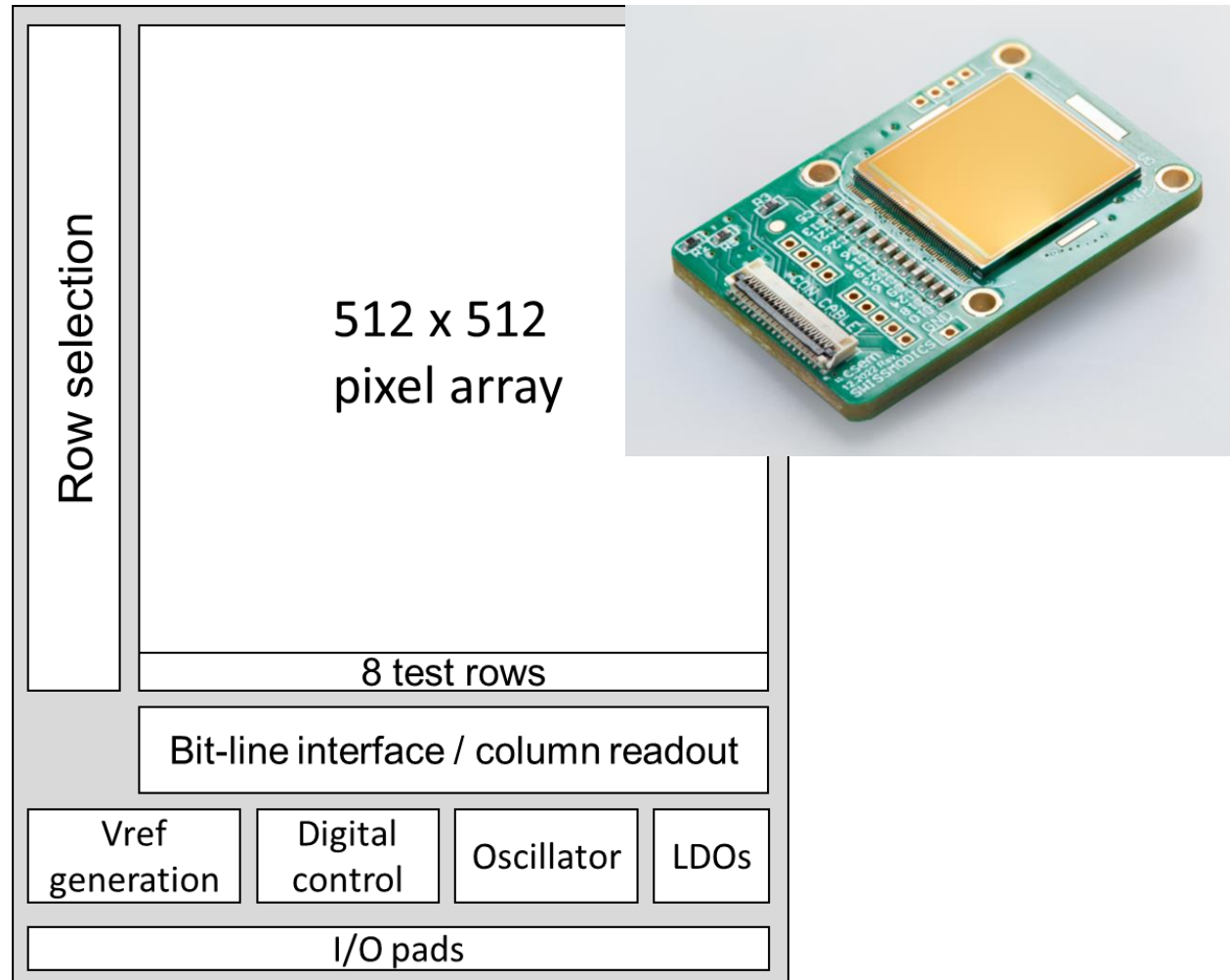
- Absorber on top of a pixel array for a 100 % fill factor
- Entire pixel area available for circuitry
- Top metal layer of the CMOS process as the in-pixel electrode
- Transparent conducting layer on top of the absorber as the global counter electrode
- Configurable pixel architecture to cope with various photon energies
- Compatible with different sensing materials (perovskite, quantum dots(QDs), ...)



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Readout chip design: design features



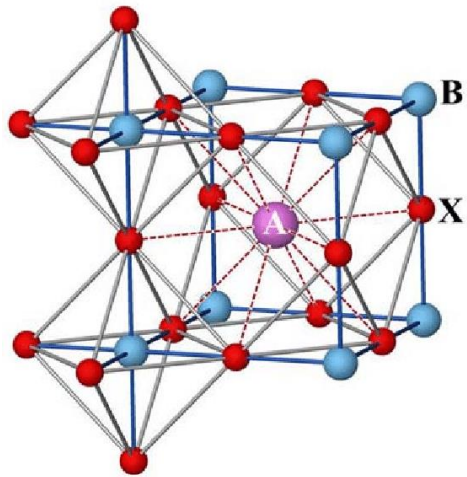
Features	Values
Supply voltage	3.3 V, 1.8 V
Pixel resolution	512 x 512
Pixel pitch	22.5 μm
Sensitivity (C_{\min})	50 $\mu\text{V}/\text{e}^-$
Full-well capacity (C_{\max})	8.5 Me-
Dynamic range	> 100 dB
Maximum frame rate	50 fps
Hole and electron collection	✓
Global shutter	Similar

Outline

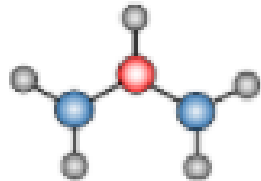
- Context
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- Step 1: readout chip design
- **Step 2: Sensor development**
 - **Sensors based on hybrid perovskites**
 - **Sensors based on quantum dots**
- Conclusions

Sensors based on hybrid perovskites

- General structure formula
 - ABX_3
 - A=cation (Inorganic Cs^+ ; organic MA^+ , FA^+)
 - B= Pb^{2+} , Sn^{2+}
 - X= I^- , Br^- , Cl^-



Methylammonium
 $MA^+(CH_3NH_2)^+$



Formamidinium
 $FA^+(CH_3NH_3)^+$

- Material properties
 - A high tolerance of defects even by solution processing
 - Low temperature budget up to 100 °C of annealing
 - Long diffusion lengths
 - Ambipolar (hole and electron) charge transport
 - A high carrier mobility
 - **An adjustable bandgap**
 - **Strong optical absorption**

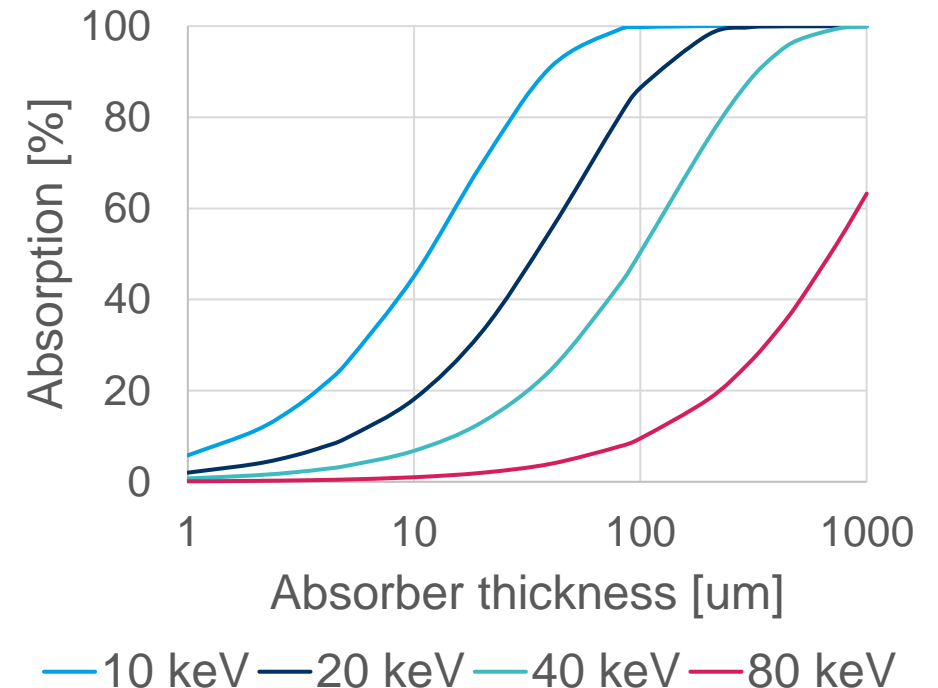
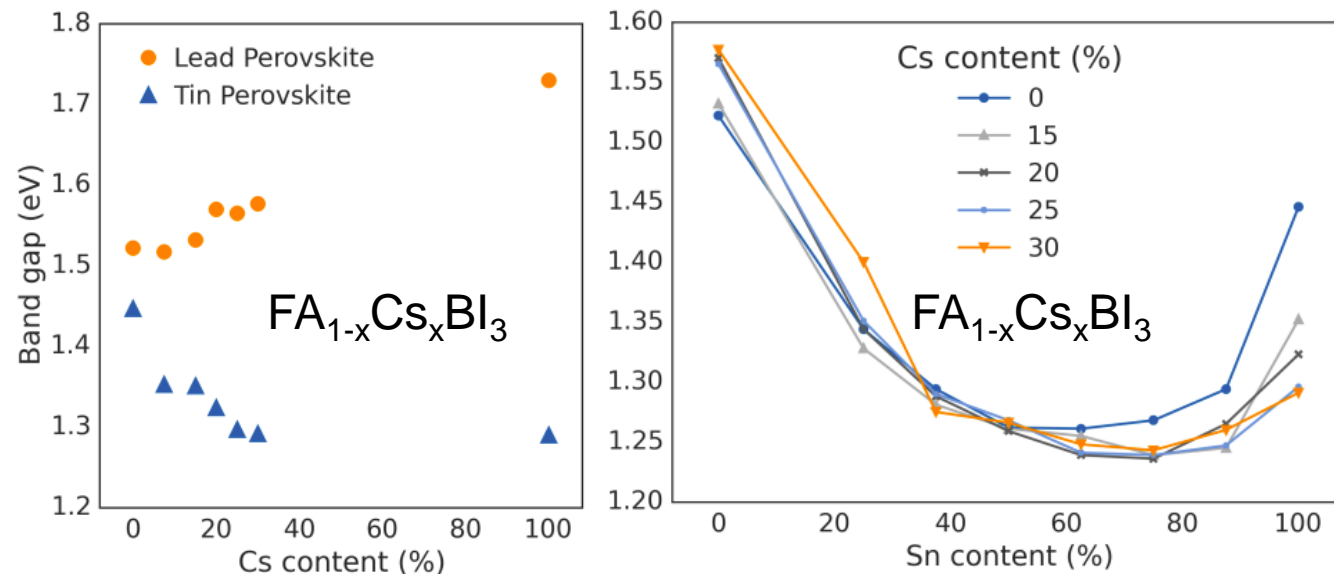
Sensors based on hybrid perovskites


- Near-infrared detection

- $\text{FA}_{0.83}\text{Cs}_{0.17}\text{Pb}_{0.5}\text{Sn}_{0.5}\text{I}_3$ with a bandgap down to 1.24 eV

- X-ray detection

- $\text{FA}_{0.83}\text{Cs}_{0.17}\text{Pb}(\text{I}_{0.83}\text{Br}_{0.17})_3$ with a high absorption coefficient even for a thin film

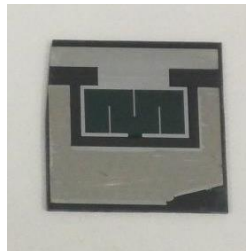
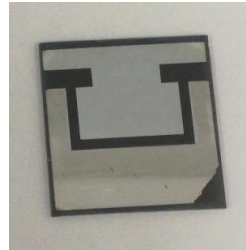
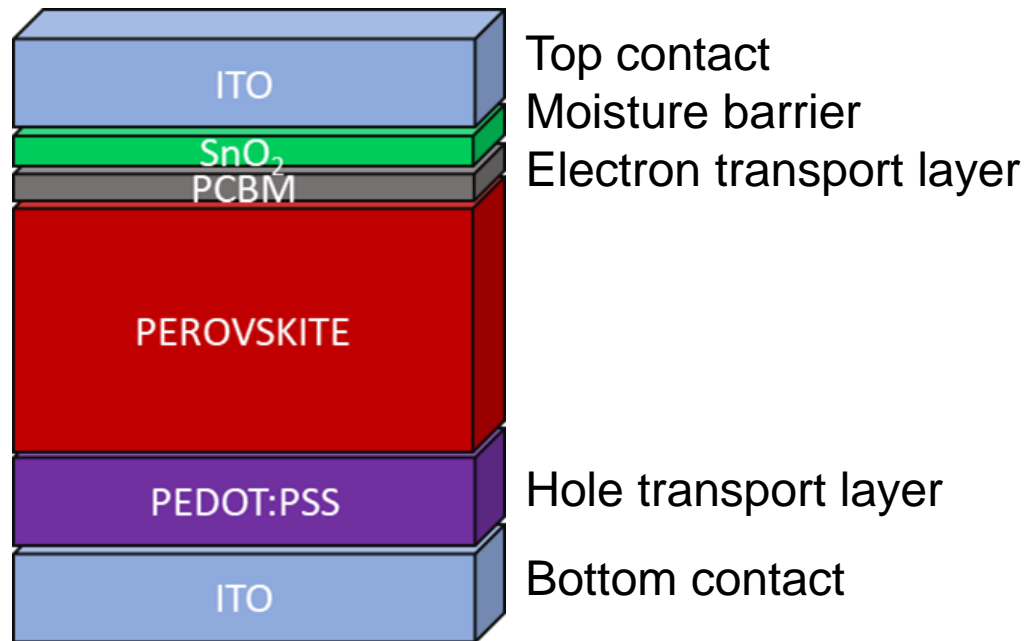


 R. Prasanna, et al., "Band Gap Tuning via Lattice Contraction and Octahedral Tilting in Perovskite Materials for Photovoltaics," J. Am. Chem. Soc. 2017, 139, 32, 11117–11124.

Sensors based on hybrid perovskites

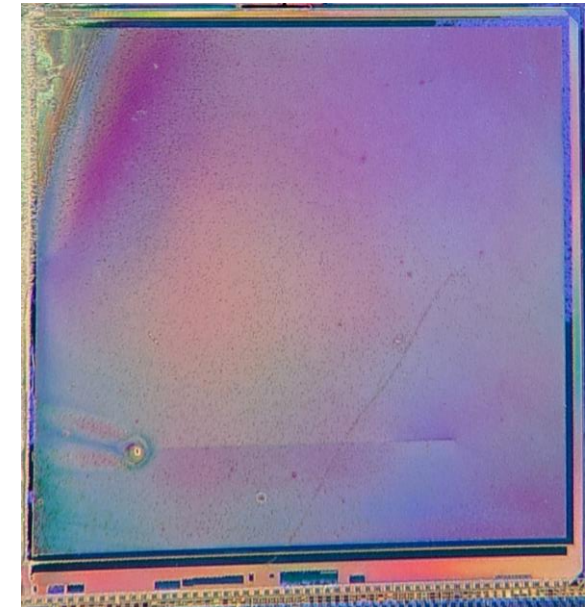
Sensor fabrication on a glass substrate

- Perovskite deposition by spin or blade coating
- First characterization to be shown



Sensor integration on our readout chips

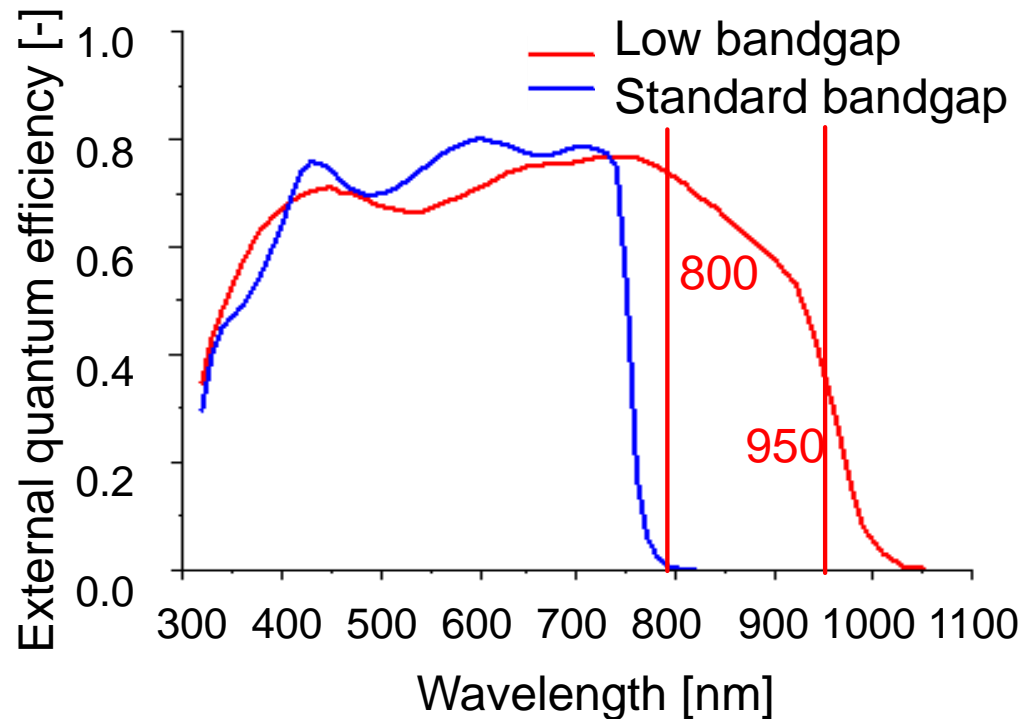
- Challenge with stability to moist
- Processed samples to be characterized



Sensors based on hybrid perovskites using a glass substrate

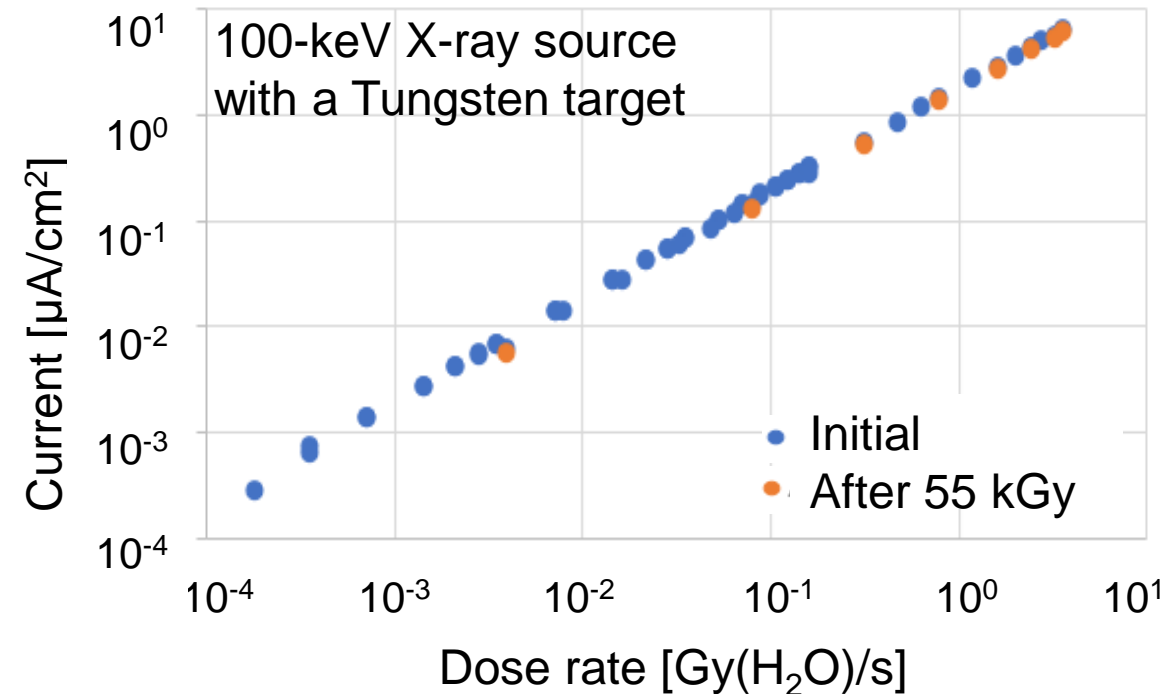
Characterization for near-infrared imaging

- Quantum efficiency above 70 % at 800 nm and 40 % up to 950 nm



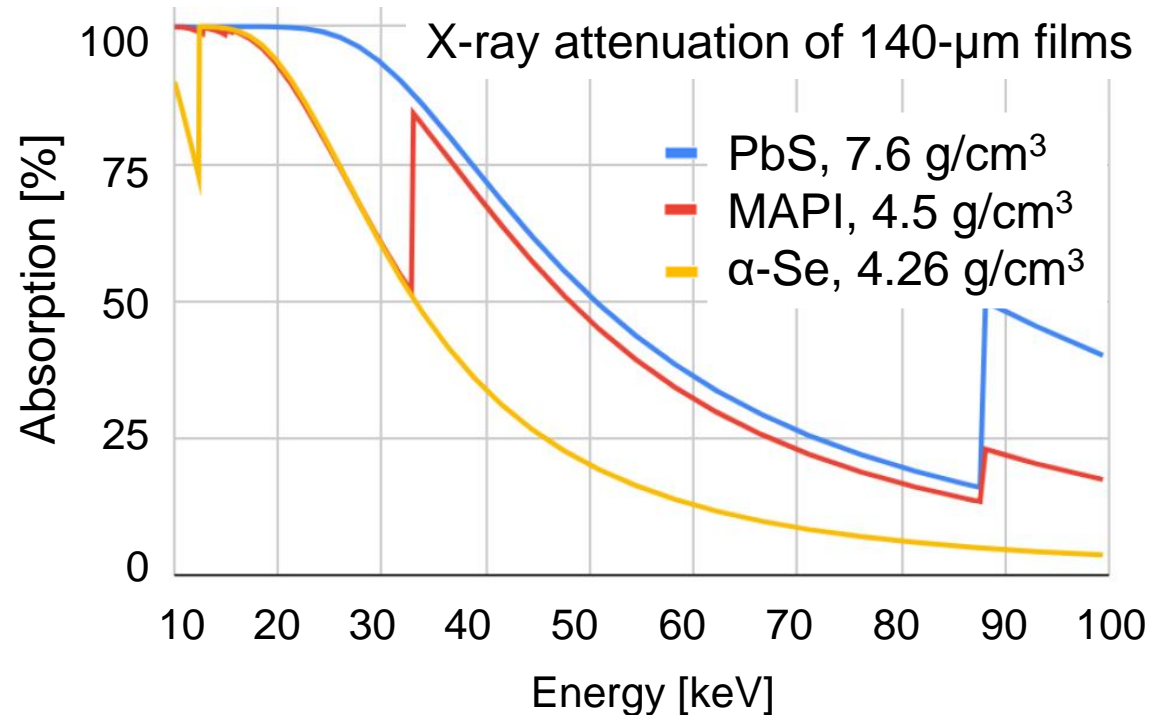
Characterization for X-ray imaging

- Good linearity over four decades
- Low response degradation after 55 kGy

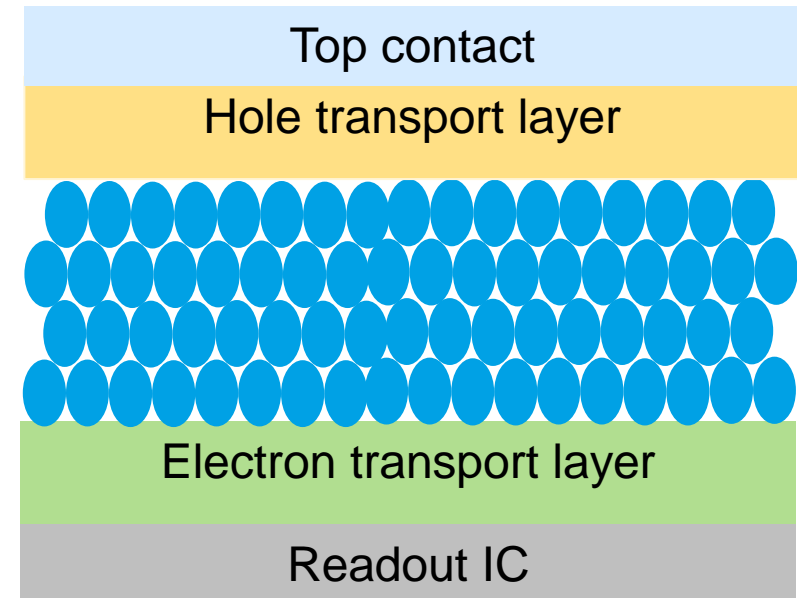


X-ray sensors based on quantum dots

- Material property
 - High absorption over a wide energy range of X-rays
- Device structure
 - Material deposition by spray coating
 - 120-um film of PbS quantum dots

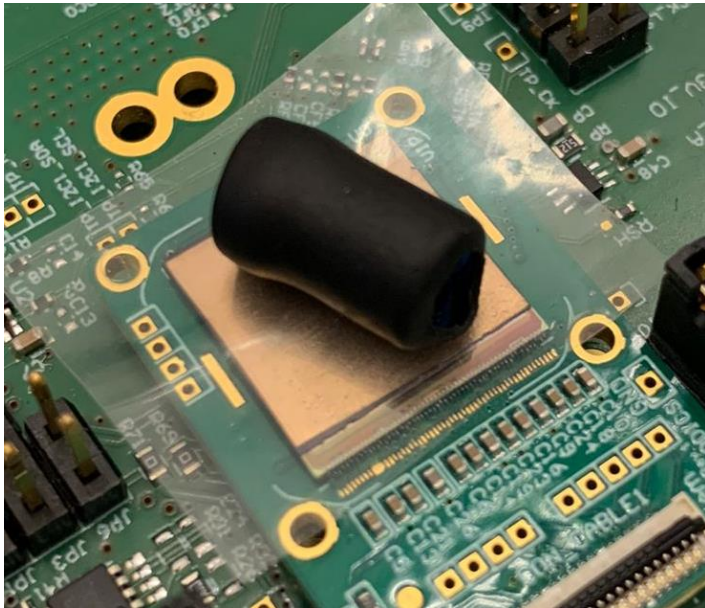


📖 This X-ray absorption plot is made from the NIST database.

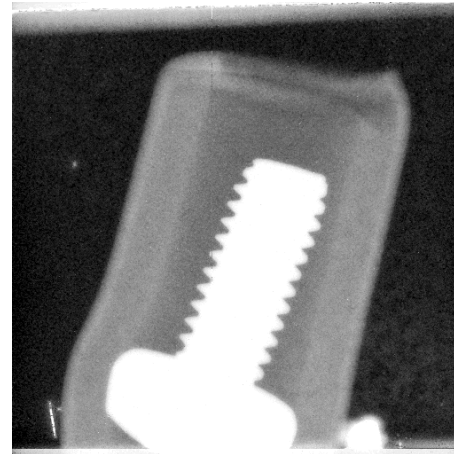


X-ray sensors based on quantum dots

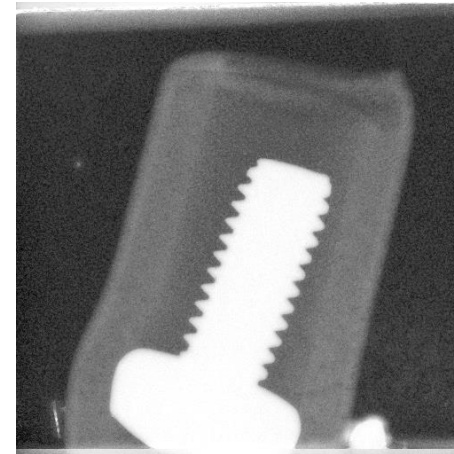
- Diode bias: 11 V



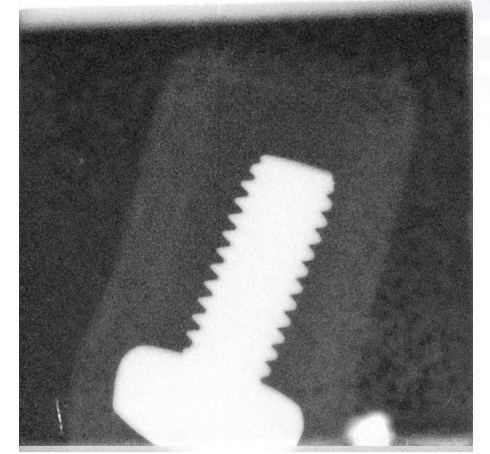
Screw in a plastic tube



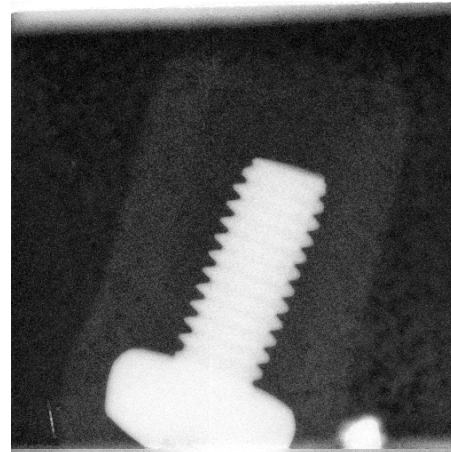
28 keV



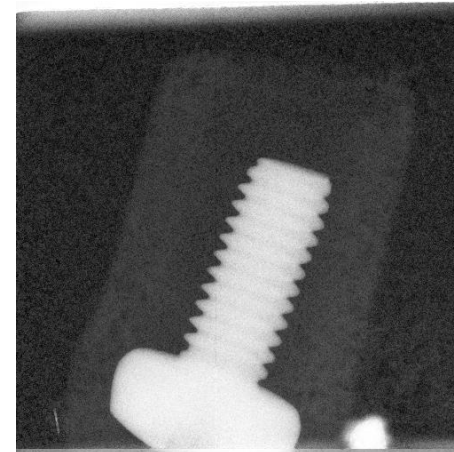
40 keV



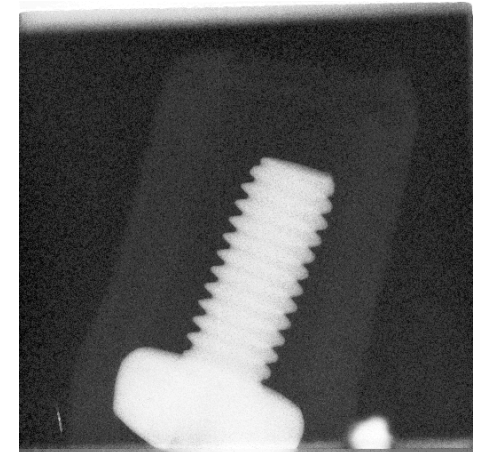
60 keV + 2-mm Al



80 keV + 2-mm Al



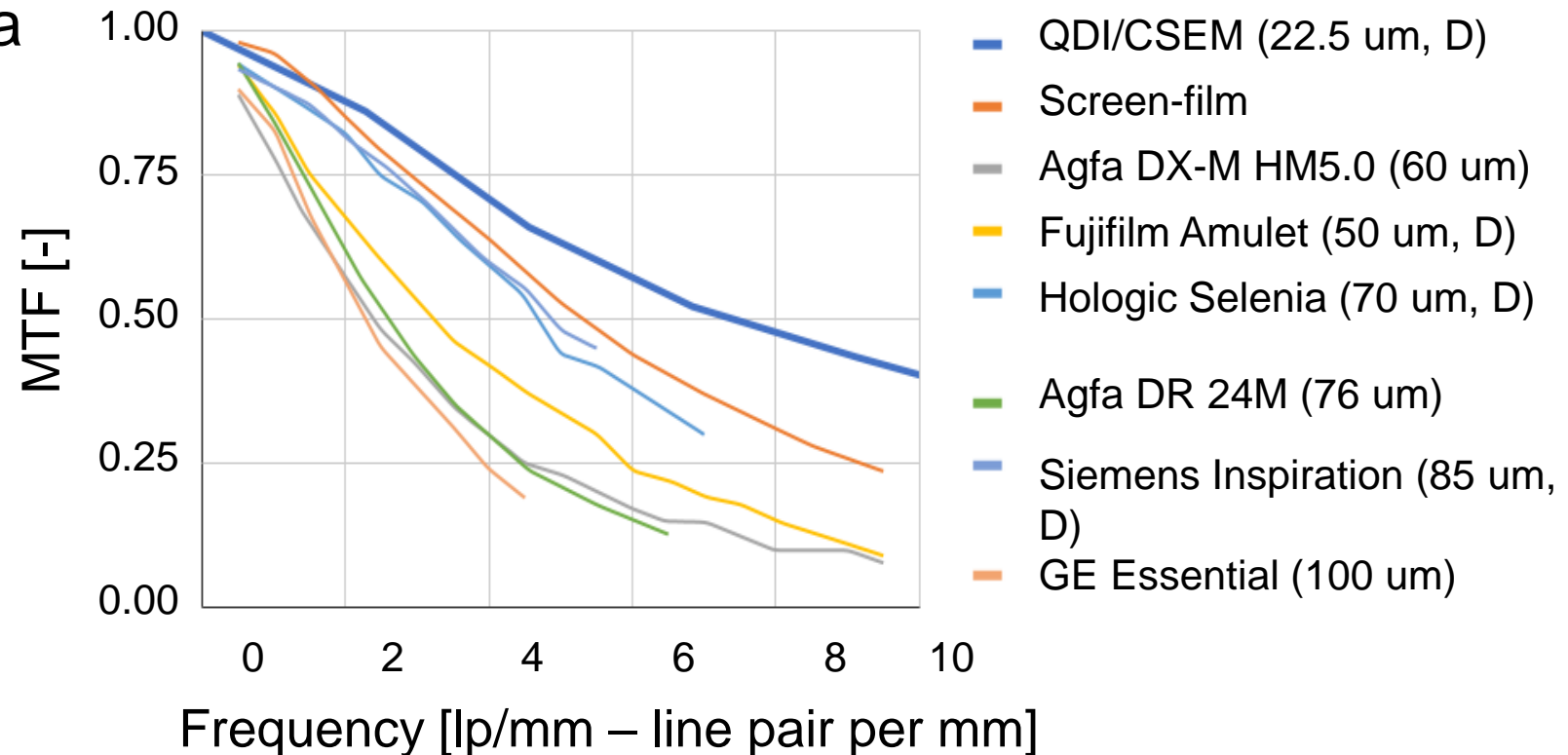
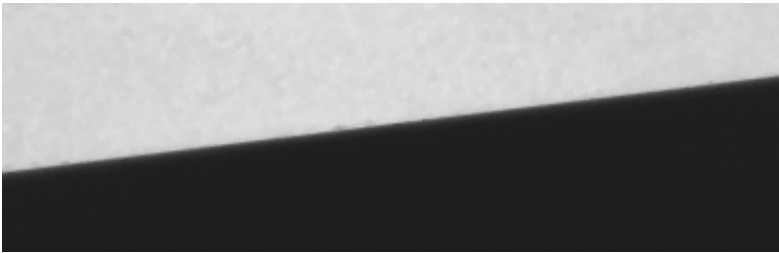
100 keV + 2-mm Al



115 keV + 2-mm Al

X-ray sensors based on quantum dots: modulated transfer function (MTF) comparison

Image of an edge taken with a 5-V bias across the diode



📖 Modified from the white paper of Agfa, "Does the pixel size of a full-field digital mammography detector matter for early detection of breast cancer?," Copyright 2019.

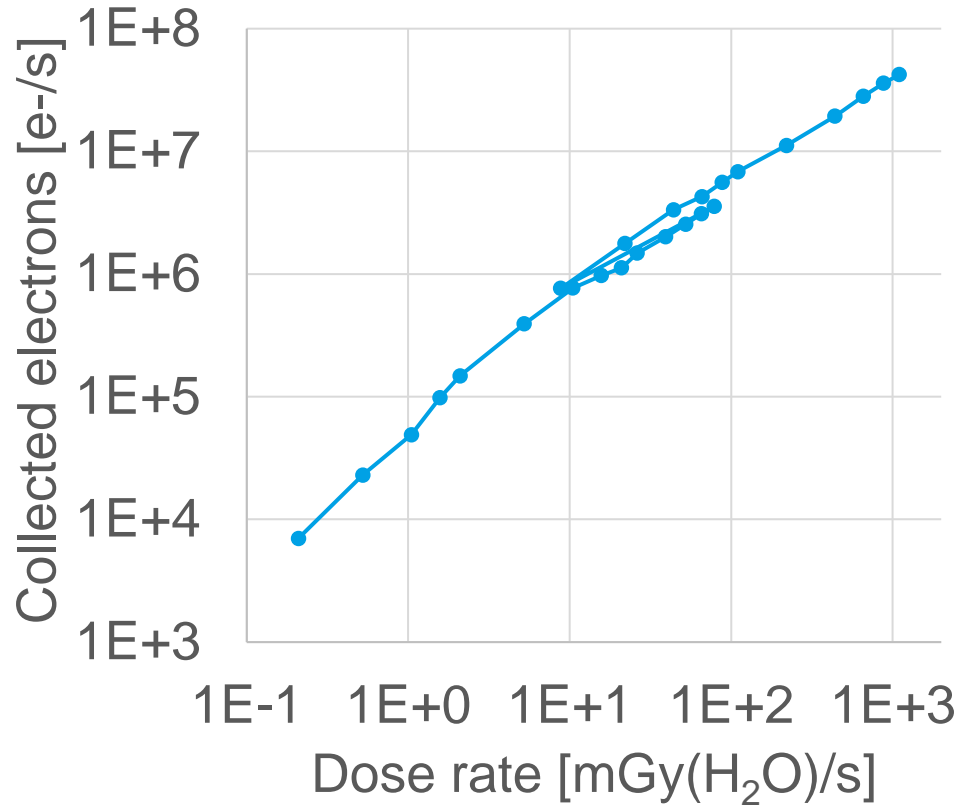
X-ray sensors based on quantum dots: noise equivalent dose (NED) comparison

Brand	Model	Pixel pitch	Technology	NED, uGy
Varex	PaxScan® 2530W	139	a-Si/GADOX	0.5
Varex	PaxScan® 2530W	139	a-Si/CsI	0.25
Trixell	Pixium® 4343 RC-e	148	a-Si/CsI	0.25
Trixell	Pixium® 4343 RC-e	148	a-Si/GADOX	0.64
Newheek	Ma1012X	85	IGZO/CsI	0.3

Brand	Pixel pitch	Technology	NED, 28 kV, uGy	NED 40kV, uGy	NED 60kV, uGy
QDI/CSEM	22.5	CMOS/QDs	1.00	0.35	0.41
QDI/CSEM	67.5 (3x3 binning)	CMOS/QDs	0.33	0.12	0.14

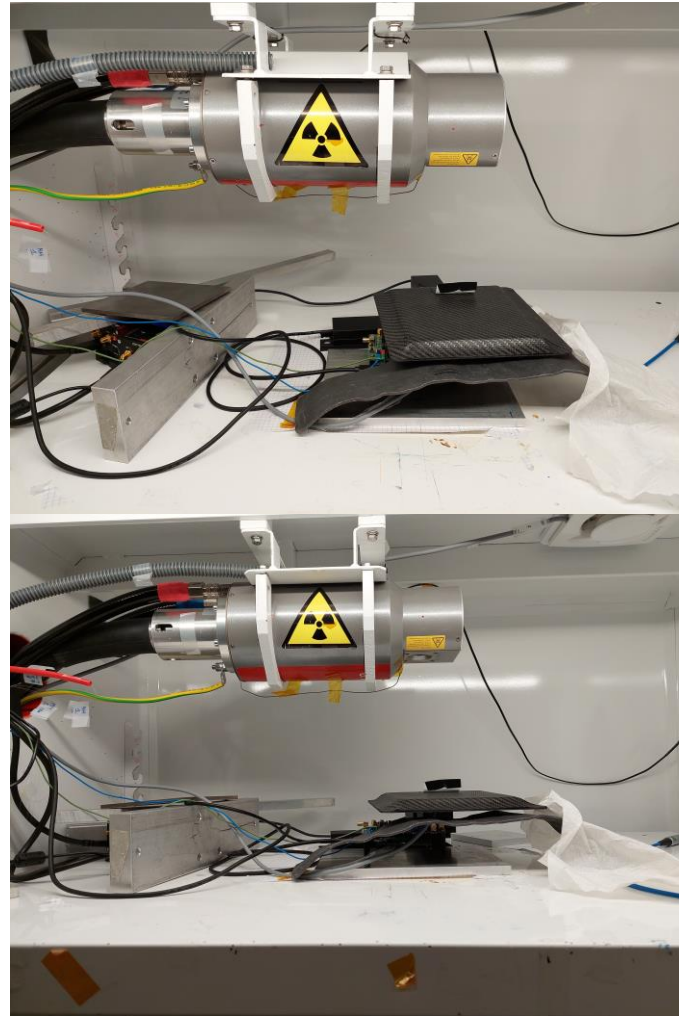
 Data is taken from product datasheets available on the website.

X-ray sensors based on quantum dots

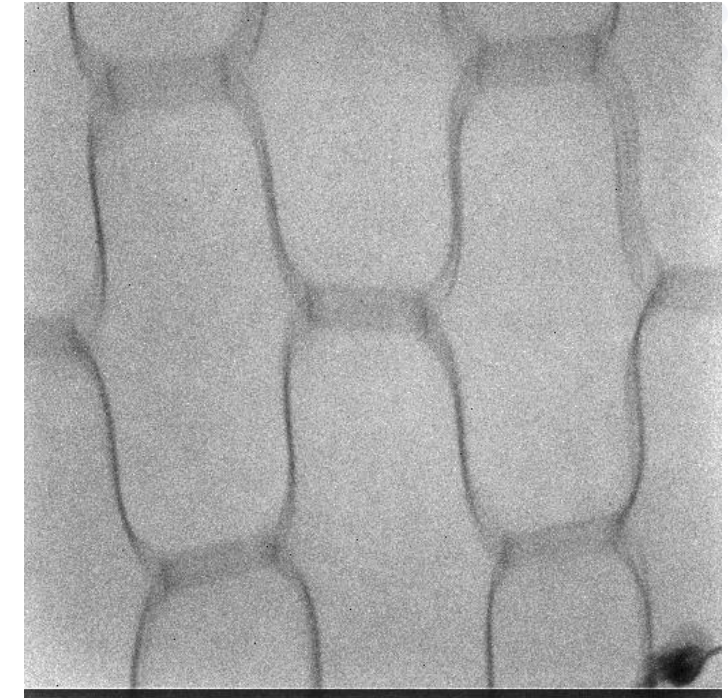


Electron flux w.r.t. dose rate

Bias only across the absorber: 5 V



X-ray setup in UJM



X-ray image of a 1.5-cm thick carbon composite

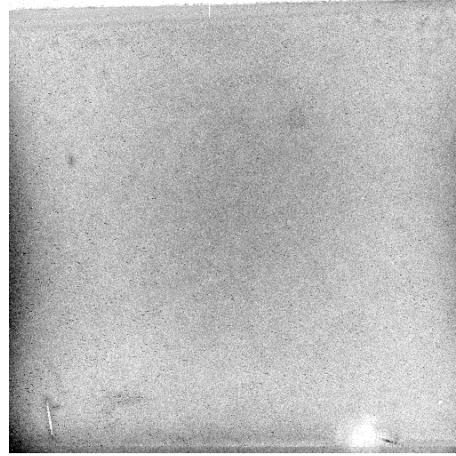
Tube voltage: 40 kV

Diode bias: 10 V

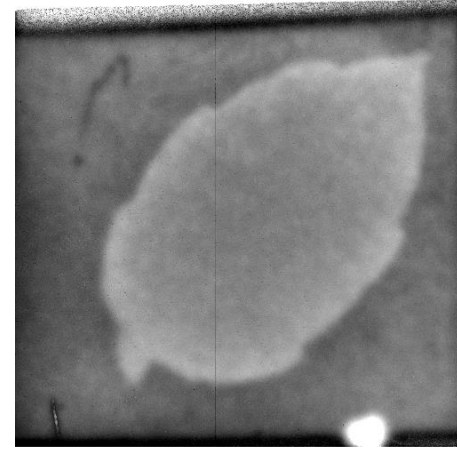
QD-based X-ray sensors sensitive to visible and short-wavelength infrared (SWIR) photons



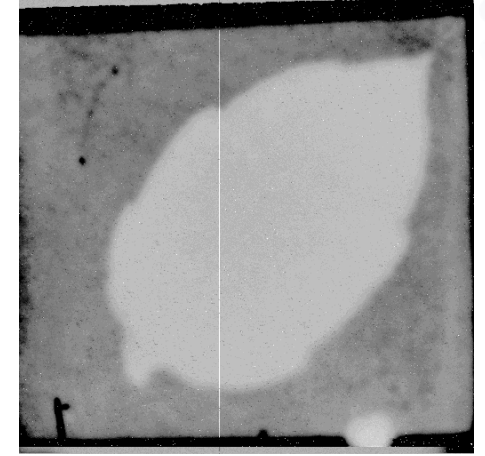
Leaf



28-keV X-ray



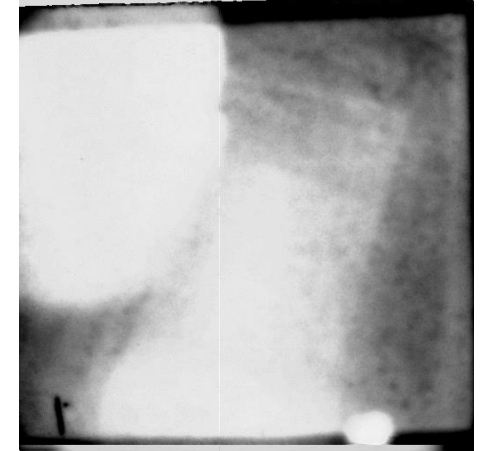
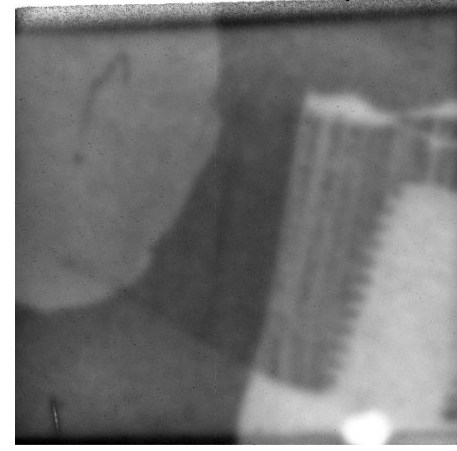
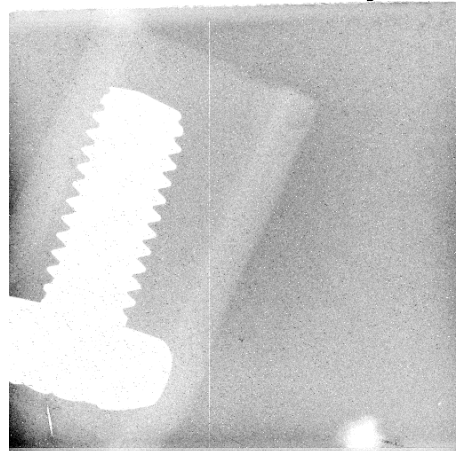
1300-nm LED (SWIR)



White LED (visible)



Screw in a tube and leaf



Conclusions

- We have developed CMOS readout chips compatible with different sensing materials.
- We have realized the first X-ray sensor based on direct conversion through PbS quantum dots.
- Our X-ray sensor achieves state-of-the-art sensitivity.
- Our X-ray sensor demonstrates potential for visible and near-infrared imaging.
- Next step
 - Detailed characterization of our exotic image sensors
 - Radiation measurements on our CMOS readout chips

Acknowledgement



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A CMOS Image Sensor with A Stacked Photon Absorber for Wide-spectral Imaging



FACING THE CHALLENGES OF OUR TIME